Results of searching in PCT for:
(mems or "micro electromechanical" or microelectromechanical) and piezoelectric near electrode* and substrate near electrode*: 5 records
Showing records 1 to 5 of 5 :

[Search Summary]

Refine Search (mems or "micro electromechanical" or microelectrome

	Title	Pub. Date	Int. Class	Applicant
1.	(WO 2006/014203) FUNCTIONAL MATERIAL FOR MICRO-MECHANICAL SYSTEMS	09.02.2006	B81B 3/00	MASSACHUSETTS INSTITUTE OF TECHNOLOGY

A **MEMS** device includes a first material structure. A second material structure includes TiN. The second material structure is moveable relative to the first material structure.

2.	(WO 2005/064701) ELECTRONIC DEVICE	14.07.2005	H01H 1/00	KONINKLIJKE PHILIPS ELECTRONICS N.V.

The **microelectromechanical** system (**MEMS**) element (101) comprises a first **electrode** (31) that is present on a surface of a **substrate** (30) and a movable element (40), which overlies at least partially the first **electrode** (31) and comprises a **piezoelectric** actuator, which movable element (40) is movable towards and from the **substrate** (30) by application of an actuation voltage between a first and a second position, in which the first position is separated from the **substrate** (30) by a gap. The **piezoelectric** actuator comprises a **piezoelectric** layer (25) which opposite surfaces is provided with a second and a third **electrode** (21,22) respectively, said second **electrode** (21) facing the **substrate** (30) and said third **electrode** (22) forming an input e...

3.	(WO 2005/001948) RADIAL BULK ANNULAR RESONATOR USING **MEMS** TECHNOLOGY	06.01.2005	H01L 41/00	THE REGENTS OF THE UNIVERSITY OF CALIFORNIA

A **MEMS** resonator includes an annular resonator body defined by an inner radius and an outer radius, a first **electrode** positioned within the inner radius and spaced from the resonator body, and a second **electrode** positioned around the annular resonator body and spaced from the outer radius. The first **electrode** and the second **electrode** provide for capacitive drive of the resonator body and capacitive sense of the resonator body. Piezo-resistive sense and **piezoelectric** drive/sense techniques can also be utilized. The overall extant can be smaller than 1 cm2 in area and positioned on a supporting **substrate** by a plurality of anchors. The **substrate** can comprise an RF transceiver integrated circuit with the anchors connecting the drive **electrode** a...

4.	(WO 2004/008635) **MICROELECTROMECHANICAL** APPARATUS AND METHODS FOR SURFACE ACOUS TIC WAVE SWITCHING	22.01.2004	H03H 9/02	INTEL CORPORATION (a Delaware Corporation) (a Delaware Corporation)

Microelectromechanical system (**MEMS**) apparatus and methods for surface acoustic wave (SAW) switching are disclosed. The apparatus includes a **piezoelectric substrate** having spaced apart input and output SAW transducers. A **MEMS** switch is arranged between the input and output SAW transducers The **MEMS** switch has a deformable member in electromagnetic communication with one or more actuation **electrodes** formed on or above the **substrate**. The deformable member is deformable to mechanically contact the **substrate** to deflect or absorb a SAW generated by the input SAW transducer.

5.	(WO 2003/010878) **MEMS** ELEMENT HAVING PERPENDICULAR PORTION FORMED FROM **SUBSTRATE**	06.02.2003	B81B 3/00	ONIX MICROSYSTEMS

Microelectromechanical systems (**MEMS**) elements, optical switches and fabrication methods are described. A **MEMS** element (101) comprises a crystalline moveable element moveably attached to a **substrate** for motion substantially perpendicular to a plane of the **substrate**. The moveable element includes a perpendicular portion (104) oriented substantially perpendicular to the **substrate**. In at least one position, a part of the perpendicular portion projects beyond a surface of the **substrate**. The perpendicular portion and **substrate** have substantially similar crystal structures. The perpendicular portion may be formed from the **substrate**. An array of such structures can implement an optical switch.

RESULT LIST
32 results found in the Worldwide database for:
Mems or "micro electromechanical" or microelectromechanical in the title AND **piezoelectric and substrate** in tl abstract
(Results are sorted by date of upload in database)

1 **Piezoelectric RF MEMS device and method of fabricating the same**
Inventor: KIM JONG-SEOK (KR); SONG IN-SANG (KR); (+5) **Applicant:** SAMSUNG ELECTRONICS CO LTD
EC: **IPC:** ***H01L41/053***; **H01L41/00**
Publication info: **US2007120445** - 2007-05-31

2 **RF MEMS switch and method for fabricating the same**
Inventor: KIM JONG-SEOK (KR); KWON SANG-WOOK (KR); (+6) **Applicant:** SAMSUNG ELECTRONICS CO LTD
EC: H01P1/12D **IPC:** ***H01P1/10***; **H01P1/10**
Publication info: **US2007115081** - 2007-05-24

3 **RF MEMS switch and fabrication method thereof**
Inventor: PARK JAE-YEONG (KR); LEE HEE-CHUL (KR) **Applicant:**
EC: **IPC:** ***H01P1/10***; **H01P1/10**
Publication info: **US2007109081** - 2007-05-17

4 **RF MEMS switch and fabrication method thereof**
Inventor: PARK JAE-YEONG (KR); LEE HEE-CHUL (KR) **Applicant:**
EC: H01P1/12D **IPC:** ***H04R17/00; H01P1/12***; **H04R17/00** (+1)
Publication info: **US2007094864** - 2007-05-03

5 **MEMS switch actuated by the electrostatic force and piezoelectric force**
Inventor: KWON SANG-WOOK (KR); KIM JUN-O (KR); (+7) **Applicant:** SAMSUNG ELECTRONICS CO LTD
EC: **IPC:** ***H01H51/22***; **H01H51/22**
Publication info: **US2007024403** - 2007-02-01

6 **Semiconductor device using piezoelectric actuator formed by use of MEMS technique**
Inventor: IKEHASHI TAMIO (JP) **Applicant:** TOKYO SHIBAURA ELECTRIC CO
EC: **IPC:** ***H01L41/00***; **H01L41/00**
Publication info: **US2006290236** - 2006-12-28

7 **METHOD FOR FABRICATING FBAR DEVICE USING MEMS METHOD**
Inventor: CHO SEONG RYEOL; JANG CHONG GYU; (+5) **Applicant:** ANTECHNOLOGY CO LTD
EC: **IPC:** ***H03H3/02***; **H03H3/00**; (IPC1-7): H03H3/02
Publication info: **KR20040052851** - 2004-06-23

8 **MEMS RF SWITCH HAVING STRUCTURE SERVING AS LEVER TRANSFERRING MOTION ON UPPER PORTION TO LOWER PORTION**
Inventor: CHO NAM GYU; LEE DAE SEONG; (+1) **Applicant:** KOREA ELECTRONICS TECHNOLOGY
EC: **IPC:** ***H01H59/00***; **H01H59/00**; (IPC1-7): H01H59/00
Publication info: **KR20040099808** - 2004-12-02

9 **FLEXIBLE MEMS TRANSDUCER, METHOD FOR MANUFACTURING THE SAME AND FLEXIBLE MEMS WIRELESS MICROPHONE**
Inventor: LEE SUK HAN; NAM YUN U **Applicant:** SAMSUNG ELECTRONICS CO LTD
EC: B81B3/00K; B81B3/00M2D; (+2) **IPC:** ***H04R17/02; B81B3/00; H01L41/09*** (+10)
Publication info: **KR20040026756** - 2004-04-01

10 **Semiconductor device formed by using MEMS technique**
Inventor: IKEHASHI TAMIO (JP) **Applicant:** TOKYO SHIBAURA ELECTRIC CO

Canadian Intellectual Property Office

Canadian Patents Database

Search Results

06/11/2007 - 15:36:48

Search Query :

((relay or switch)) <AND> (((mems o

Query: ((relay or switch)) <AND> (((mems or "micro electromechanical" or microelectromechanical)) <in> abstract) <AND> (((piezoelectric and substrate and electrode*)) <in> claims)

2 documents out of 1914183 matched your query. Click on its number to view the details of the document.

Note: All document detail pages now appear on a new Browser Window.

1.	2377377	OPTO-MECHANICAL VALVE AND VALVE ARRAY FOR FIBER-OPTIC COMMUNICATION	80%
2.	2379936	OPTO-MECHANICAL VALVE AND VALVE ARRAY FOR FIBER-OPTIC COMMUNICATION	77%

Important Notices

	Type	L #	Hits	Search Text	DBs	Time Stamp	Comments
1	BRS	L1	33	piezoelectric adj3 (relay or switch) same electrode same substrate and 310/346,353, 352	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	2007/06/11 14:55	

Searching PAJ

MENU NEWS HELP

Search Results : 0

Clear

Text Search

If you want to conduct a Number Search, please click on the button to the right. Number Search

Applicant,Title of invention,Abstract --- e.g. computer semiconductor

If you use the AND/OR operation, please leave a SPACE between keywords.
One letter word or Stopwords are not searchable.

mems piezoelectric AND

AND

electrode substrate AND

AND

relay switch OR

AND

Date of publication of application --- e.g.19980401 - 19980405

-

AND

IPC --- e.g. D01B7/04 A01C11/02

If you use the OR operation, please leave a SPACE between keywords.

Search Stored data

Searching PAJ

MENU | NEWS | HELP

Search Results : 0

Clear

Text Search

If you want to conduct a Number Search, please click on the button to the right. Number Search

Applicant,Title of invention,Abstract --- e.g. computer semiconductor

If you use the AND/OR operation, please leave a SPACE between keywords.

One letter word or Stopwords are not searchable.

micro electromechanical piezoelectric AND

AND

electrode substrate AND

AND

relay switch OR

AND

Date of publication of application --- e.g.19980401 - 19980405

-

AND

IPC --- e.g. D01B7/04 A01C11/02

If you use the OR operation, please leave a SPACE between keywords.

Search Stored data

Searching PAJ

MENU | NEWS | HELP

Search Results : 72

Index Indication | Clear

Text Search

If you want to conduct a Number Search, please click on the button to the right. Number Search

Applicant,Title of invention,Abstract --- e.g. computer semiconductor

If you use the AND/OR operation, please leave a SPACE between keywords.

One letter word or Stopwords are not searchable.

piezoelectric AND

AND

electrode substrate AND

AND

relay switch OR

AND

Date of publication of application --- e.g.19980401 - 19980405

\-

AND

IPC --- e.g. D01B7/04 A01C11/02

If you use the OR operation, please leave a SPACE between keywords.

Search | Stored data